IN THE CLAIMS:

5

10

- 1.-34. (Cancelled)
- (New) A semiconductor light emitting device comprising:
 - a base substrate;
- a multilayer epitaxial structure includes a first conductive layer, a second conductive layer and a light emitting layer that is formed between the first conductive layer and the second conductive layer, the multilayer epitaxial structure being formed on the base substrate in such a manner that the first conductive layer is positioned closer to the base substrate than the second conductive layer is;
 - a first electrode that is formed on the first conductive layer;
 - a second electrode that is formed on the second conductive layer;
- a first power supply terminal and a second power supply terminal that are formed on a main surface of the base substrate which faces away from the multilayer epitaxial structure;
- a first conductive member including a first through hole that is provided in the base substrate, and electrically connecting the first electrode and the first power supply terminal;
- a second conductive member including a second through hole that is provided in

 the base substrate, and electrically connecting the second electrode and the second power supply terminal: and
 - a phosphor film that covers a main surface of the multilayer epitaxial structure which faces away from the base substrate, and every side surface of the multilayer epitaxial structure from a layer including the main surface to include at least the light emitting layer.

- 36. (New) The semiconductor light emitting device of Claim 35, wherein the multilayer epitaxial structure is formed on the base substrate leaving a space along each edge of a main surface of the base substrate which faces the multilayer epitaxial structure; and
- the first through hole and the second through hole are provided in a peripheral portion of the base substrate, the peripheral portion corresponding to the space.
 - 37. (New) The semiconductor light emitting device of Claim 35, further comprising: a metal reflective film that is sandwiched between the multilayer epitaxial structure and the base substrate.
 - 38. (New) The semiconductor light emitting device of Claim 35, wherein the first conductive layer is a p-type semiconductor layer, and the second conductive layer is an n-type semiconductor layer.
 - 39. (New) The semiconductor light emitting device of Claim 38, wherein a main surface of the n-type semiconductor layer which faces away from the light emitting layer is uneven so as to improve light extraction efficiency.
 - 40. (New) The semiconductor light emitting device of Claim 35 wherein the multilayer epitaxial structure is formed through epitaxial growth, on a singlecrystal substrate different from the base substrate, and transferred from the single-crystal substrate to the base substrate.

5

- 41. (New) The semiconductor light emitting device of Claim 40, wherein
- the multilayer epitaxial structure is transferred to the base substrate in such a manner that a last epitaxially-grown layer having grown on the single-crystal substrate is positioned closer to the base substrate than a first epitaxially-grown layer is.
- (New) The semiconductor light emitting device of Claim 35 wherein the base substrate is a SiC substrate.
- 43. (New) The semiconductor light emitting device of Claim 35 wherein the epitaxial structure has an uneven p-electrode surface as a second conductive layer.
- 44. (New) The semiconductor light emitting device of Claim 43 wherein a plurality of depressions is formed on a surface of the p-electrode surface to improve light extraction efficiency.
- 45. (New) The semiconductor light emitting device of Claim 43 wherein a Ni/An thin film and an ITO transparent electrode form the p-electrode.